

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:

Hidekazu MIYAIRI et al.

Serial No. 10/663,671

Filed: September 17, 2003

For: LASER APPARATUS, LASER IRRADIATION  
METHOD, AND MANUFACTURING METHOD  
OF SEMICONDUCTOR DEVICE



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Group Art Unit: 1722  
Examiner: Felisa Carla Hiteshew  
)  
Date: January 11, 2006

**RESPONSE TO REQUEST FOR RESTRICTION REQUIREMENT**

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Request for Restriction Response mailed December 12, 2005,  
Applicants responds as follows: